

A DEVICE MEASURING A PHYSICAL STATE OF A MATERIAL BY SPECTRUM AND A METHOD THEREOF

ABSTRACT

The present invention is a device and a method thereof measuring a physical state of a material by spectrum, the device comprising: a first action path where a material to be measured is contained; a detecting unit detecting a spectrum; and a processing unit obtaining a deposition state relating to the material to be measured based on the spectrum. An advance monitoring can be supplied when a deposit is formed by the present invention, therefore, the deposition process can be observed and/or controlled immediately, and the yield and degree of automation will be greatly improved.

(FIG. 1)